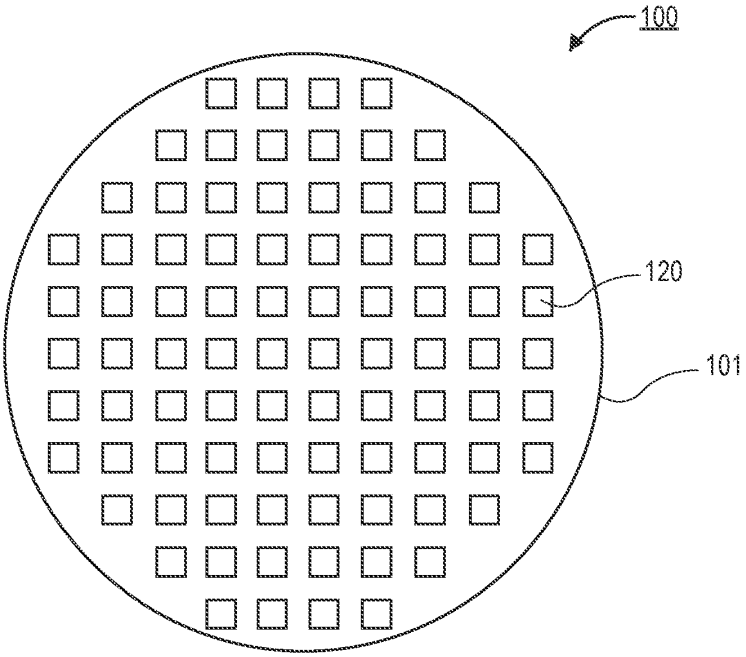


FIG. 1

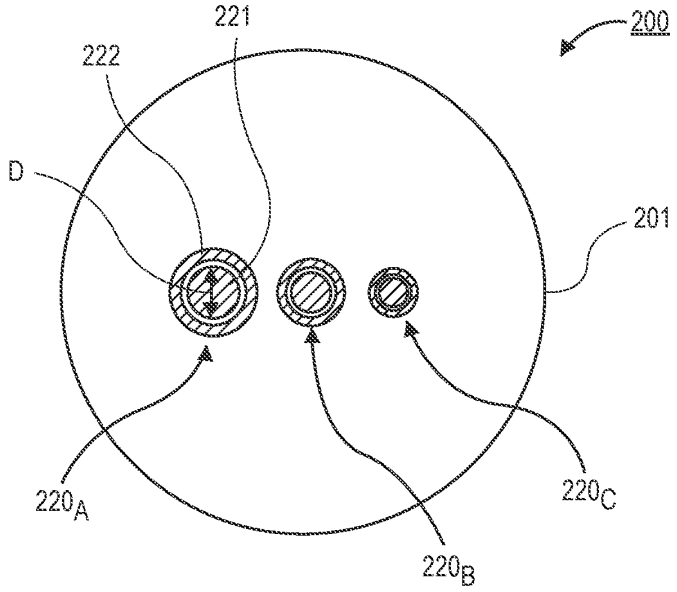


FIG. 2

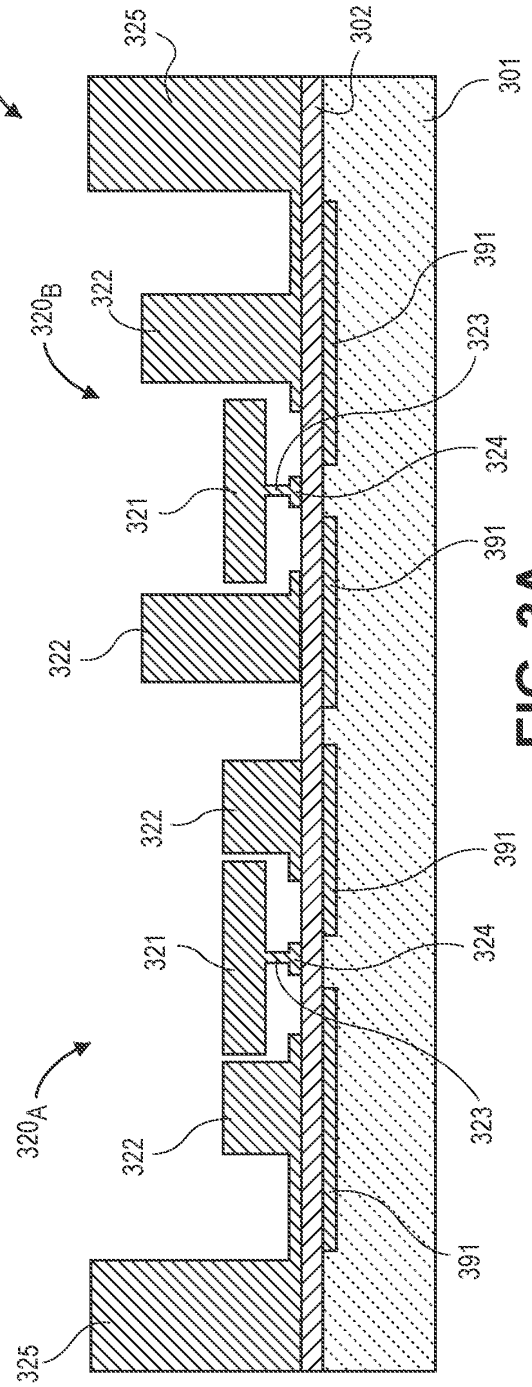

300
325
302
301
391
322
323
321
324
320_B
320_A

FIG. 3A

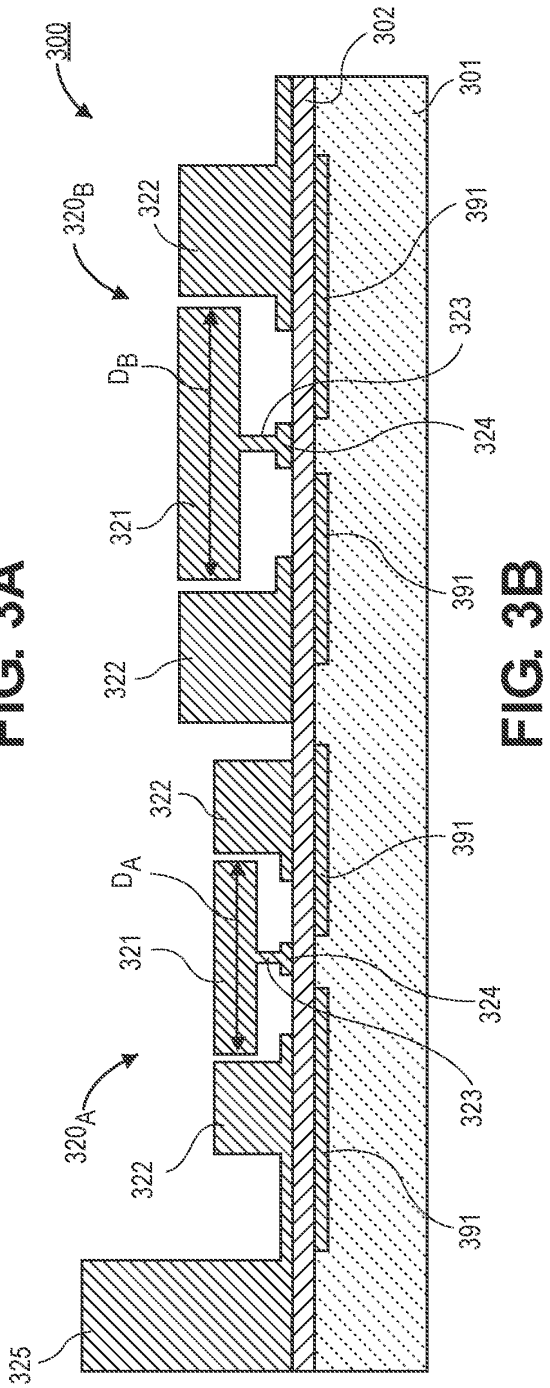

300
302
301
391
322
323
324
D_B
D_A
321
320_B
320_A
325

FIG. 3B

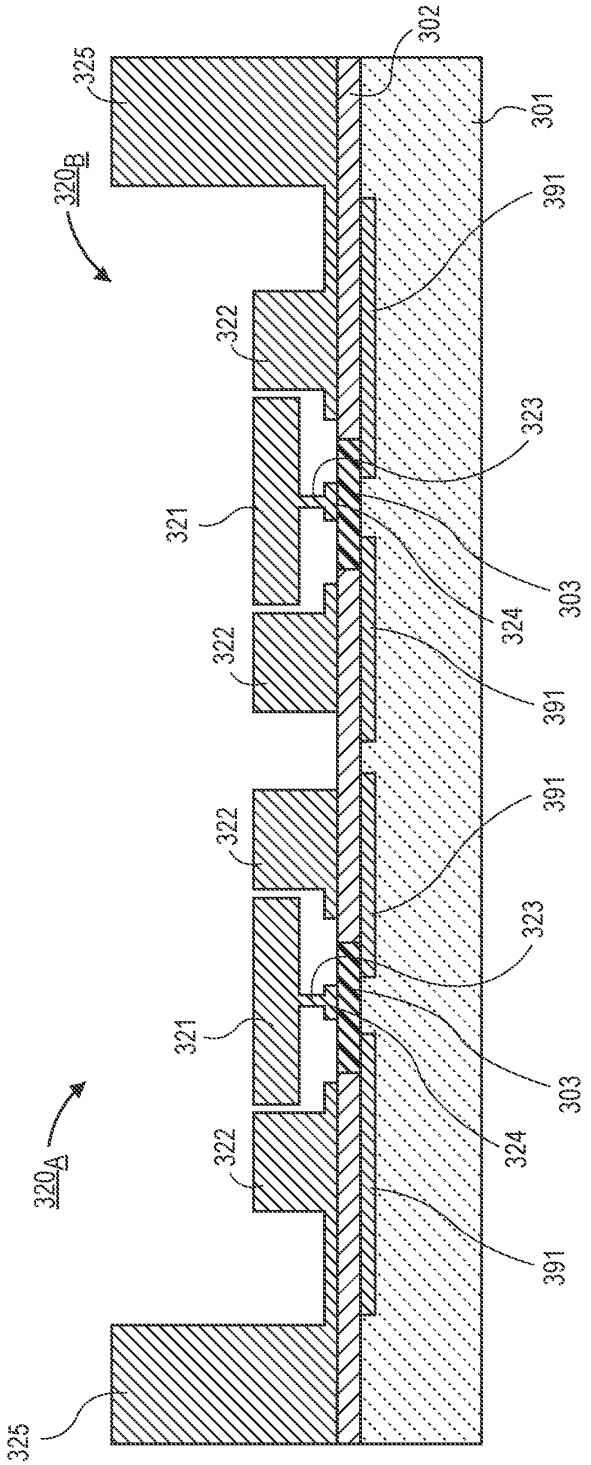

300
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302
301
320B
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303
324
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391
391
322
323
321
303
324
322
391
320A
325

FIG. 3C

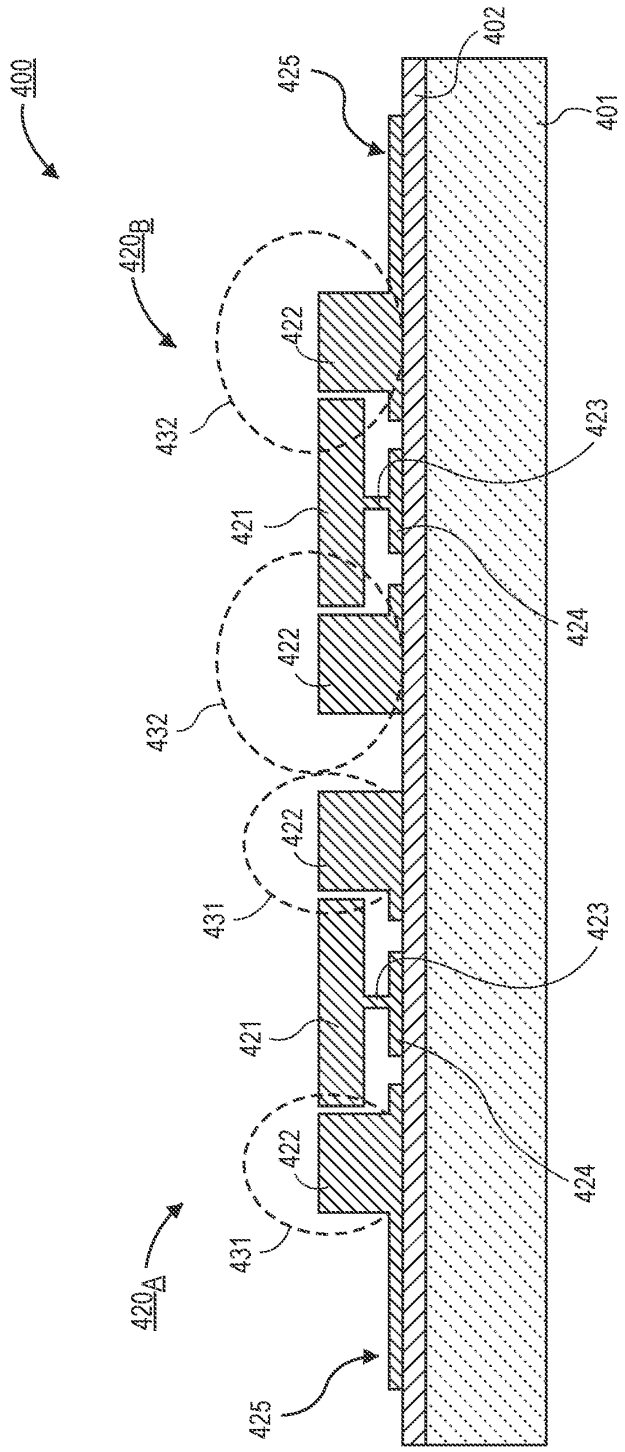

400
402
425
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420B
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431
423
421
422
424
431
420A
425

FIG. 4

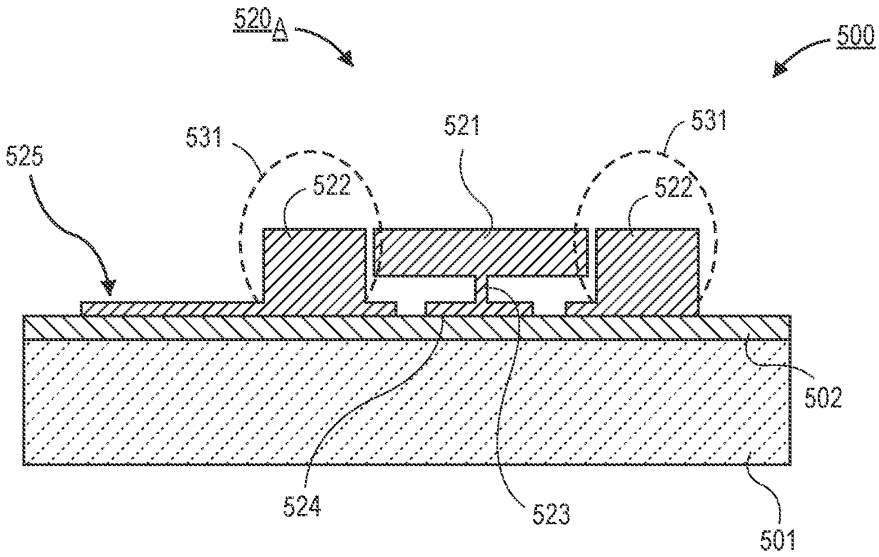

520A
500
531
521
531
525
522
522
502
524
523
501

FIG. 5A

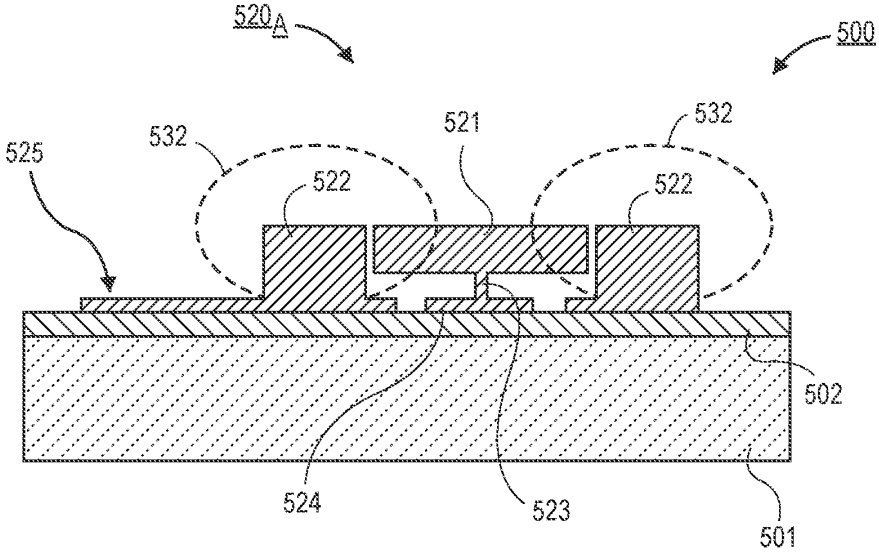

520A
500
532
521
532
525
522
522
502
524
523
501

FIG. 5B

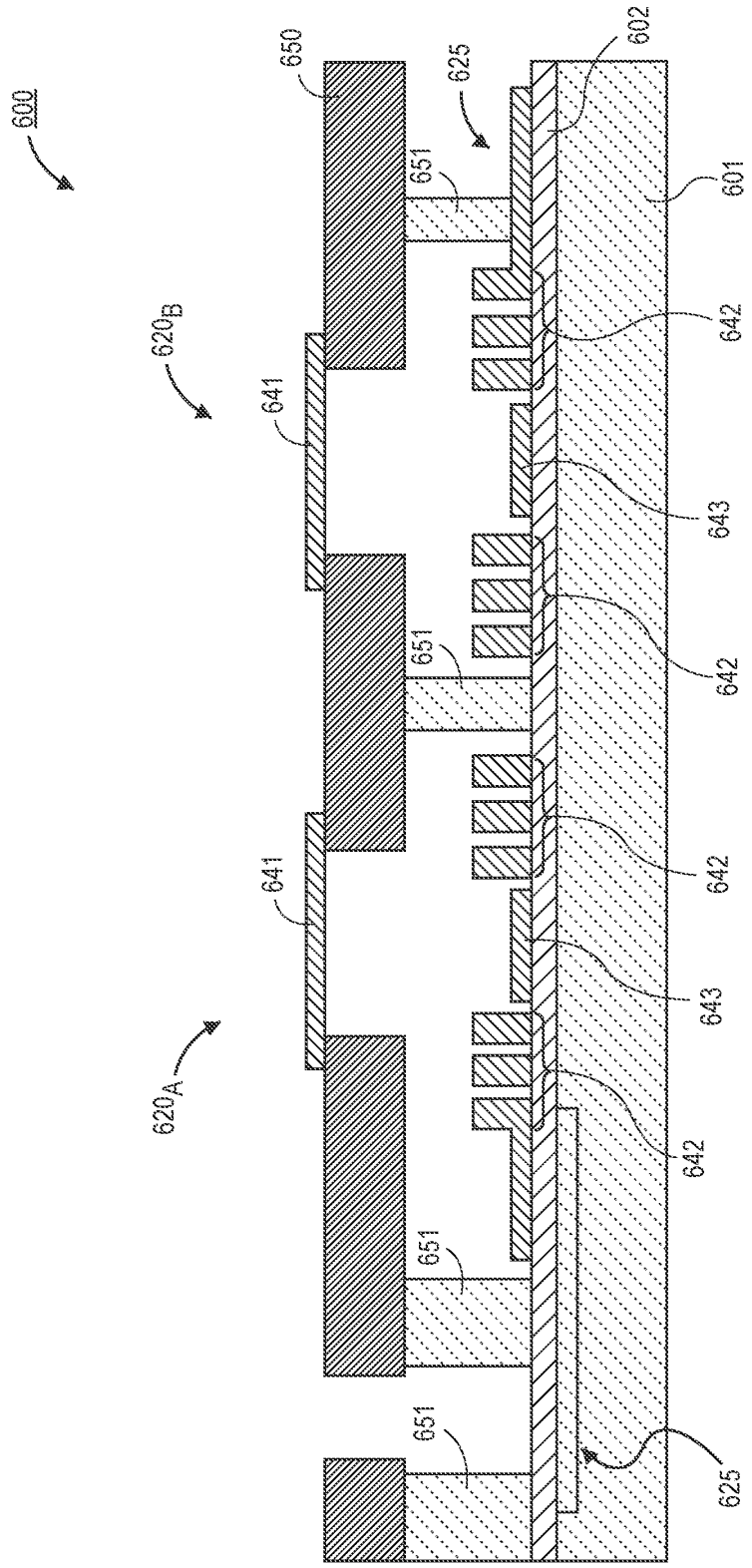

600
650
625
602
651
601
620B
641
642
643
651
642
641
643
620A
642
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651
625

FIG. 6A

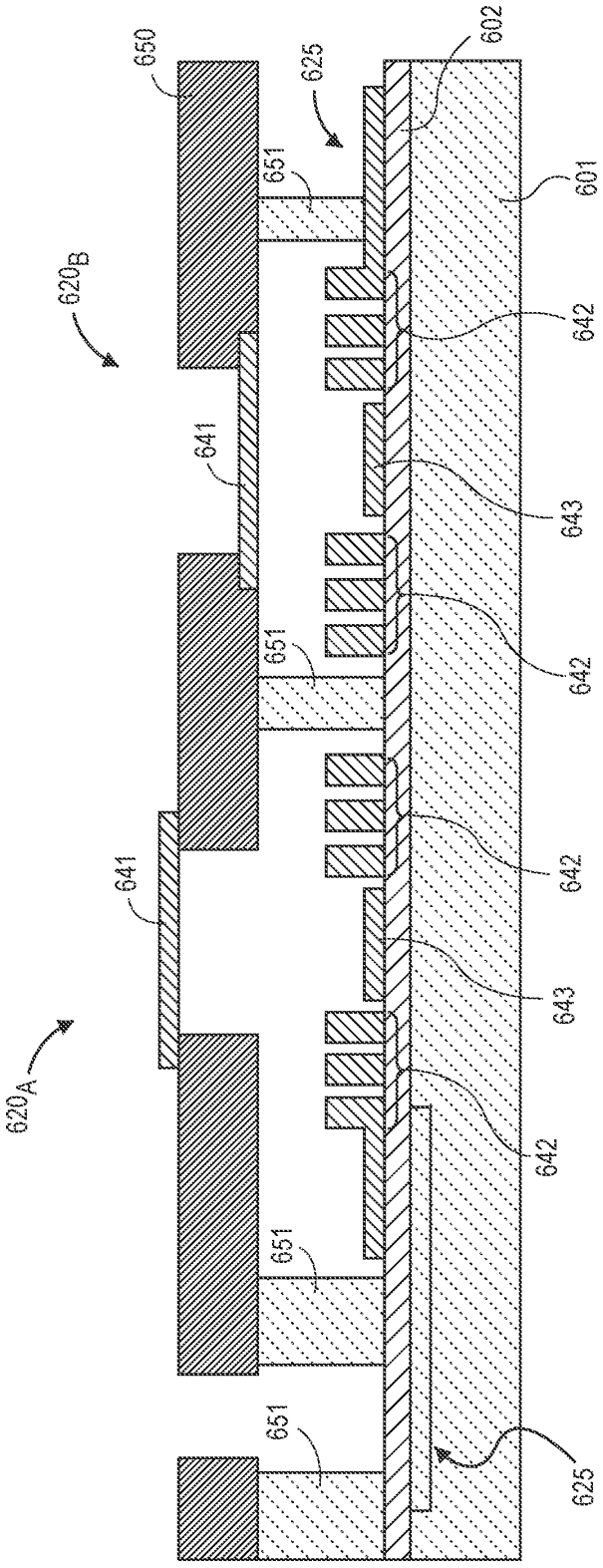

600
650
625
602
651
601
620B
642
641
643
651
642
641
642
620A
643
642
651
651
625

FIG. 6B

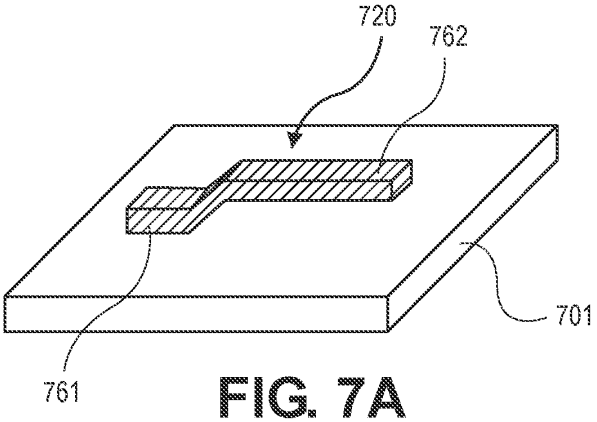


FIG. 7A

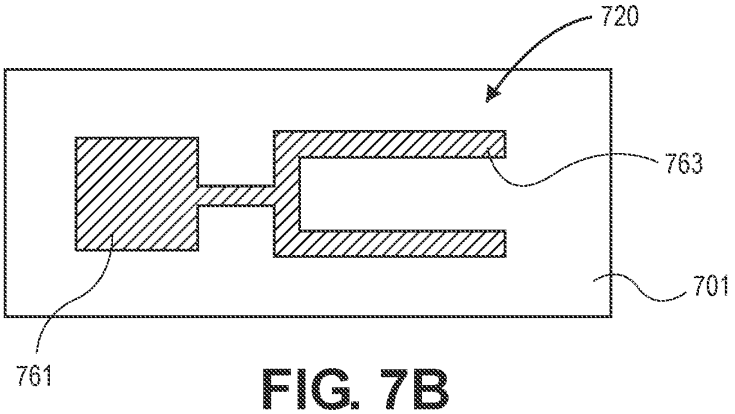


FIG. 7B

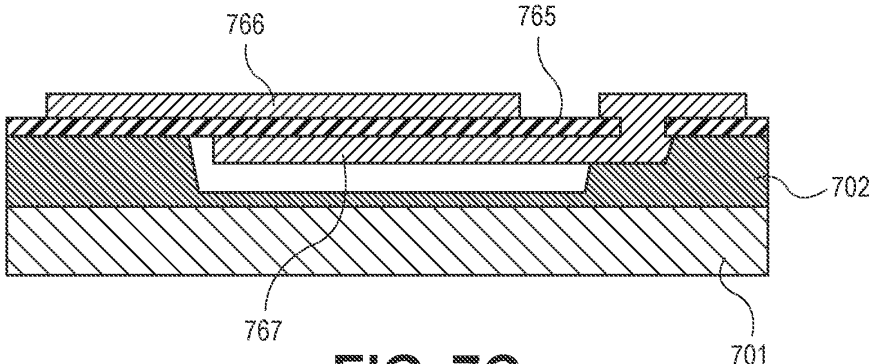


FIG. 7C

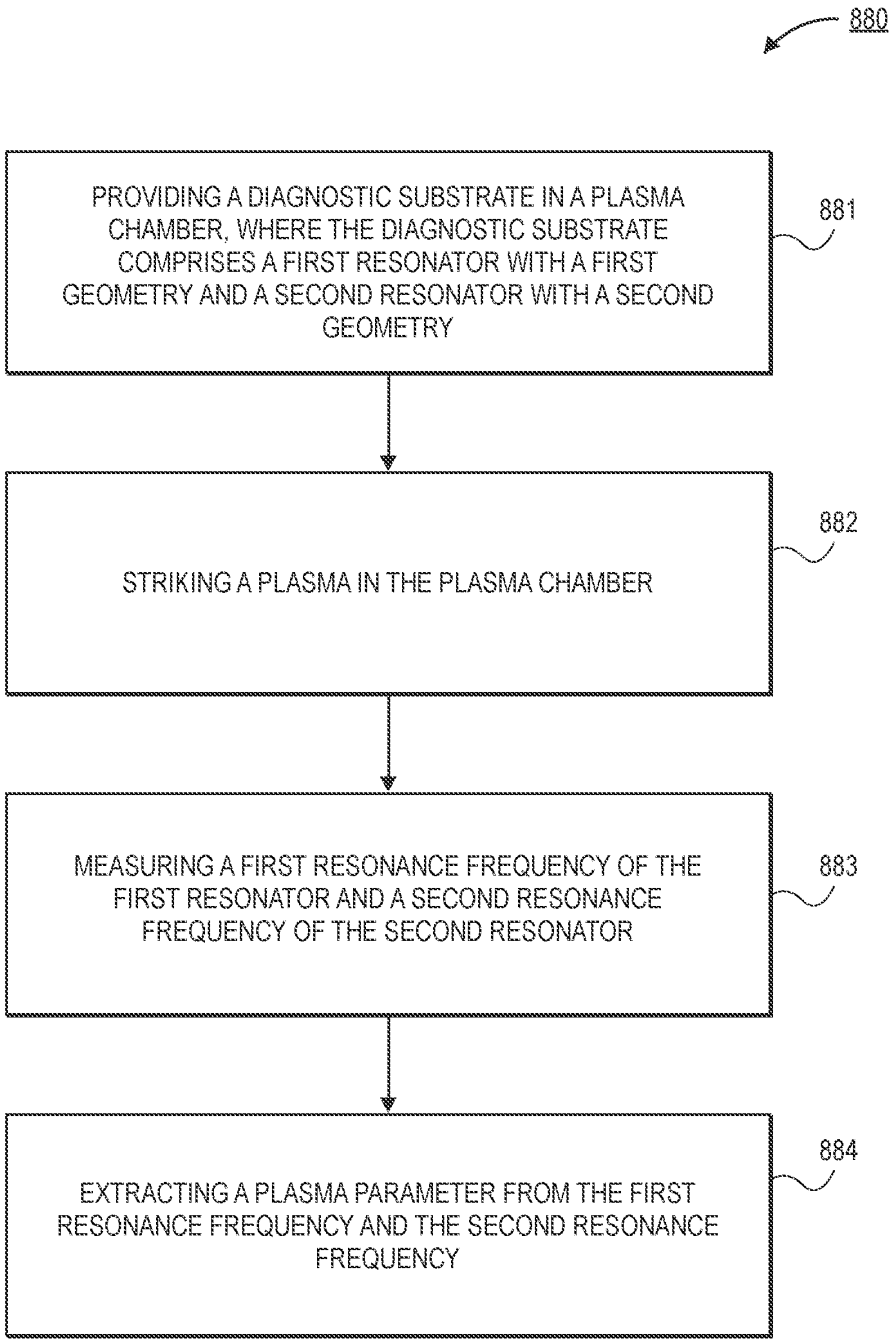

880
PROVIDING A DIAGNOSTIC SUBSTRATE IN A PLASMA CHAMBER, WHERE THE DIAGNOSTIC SUBSTRATE COMPRISES A FIRST RESONATOR WITH A FIRST GEOMETRY AND A SECOND RESONATOR WITH A SECOND GEOMETRY
881
STRIKING A PLASMA IN THE PLASMA CHAMBER
882
MEASURING A FIRST RESONANCE FREQUENCY OF THE FIRST RESONATOR AND A SECOND RESONANCE FREQUENCY OF THE SECOND RESONATOR
883
EXTRACTING A PLASMA PARAMETER FROM THE FIRST RESONANCE FREQUENCY AND THE SECOND RESONANCE FREQUENCY
884

FIG. 8

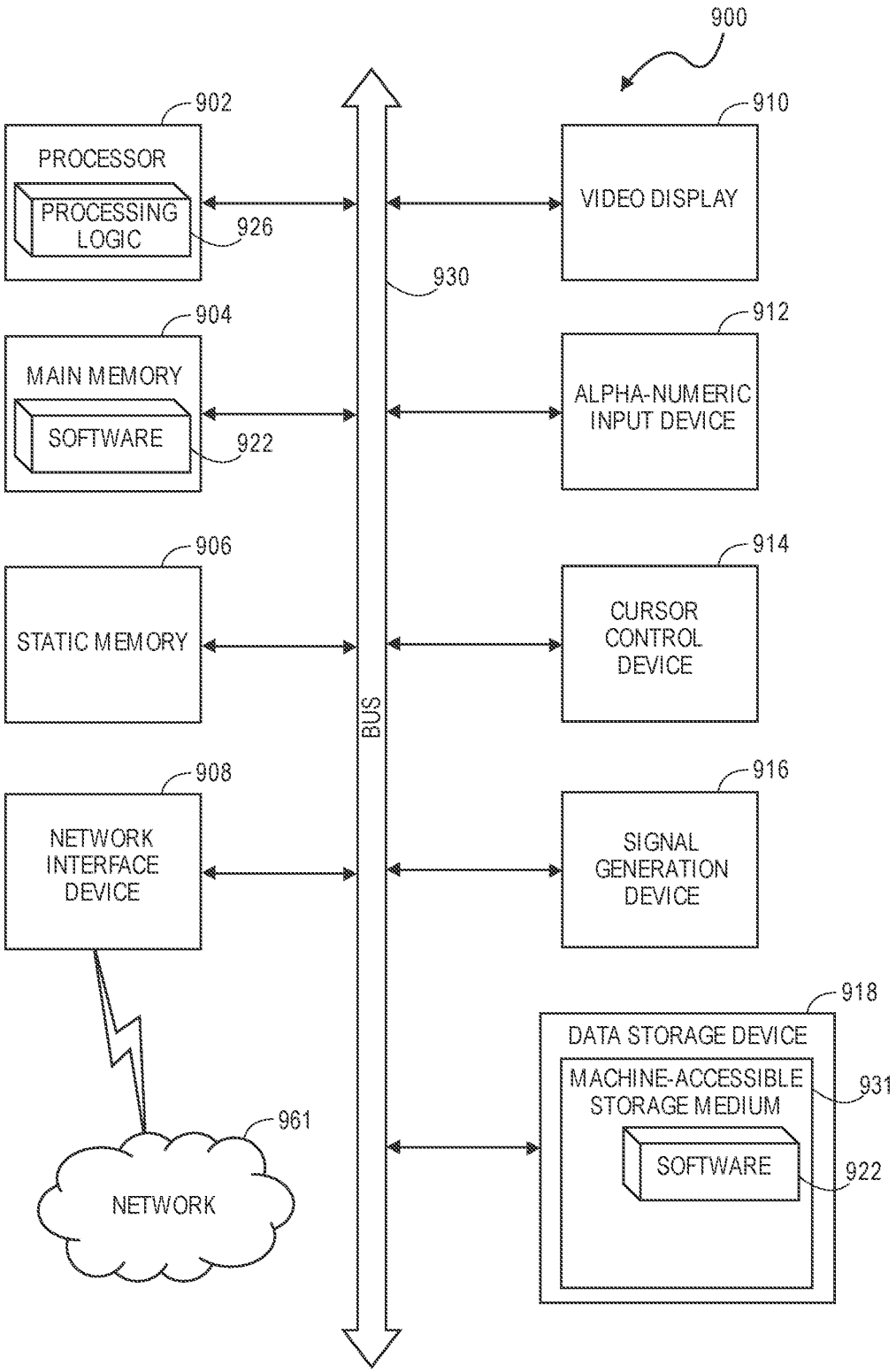

900
902
PROCESSOR
PROCESSING LOGIC
926
904
MAIN MEMORY
SOFTWARE
922
906
STATIC MEMORY
908
NETWORK INTERFACE DEVICE
961
NETWORK
930
BUS
910
VIDEO DISPLAY
912
ALPHA-NUMERIC INPUT DEVICE
914
CURSOR CONTROL DEVICE
916
SIGNAL GENERATION DEVICE
918
DATA STORAGE DEVICE
MACHINE-ACCESSIBLE STORAGE MEDIUM
931
SOFTWARE
922

FIG. 9